

## **PROGRAM (tentative)**

### **March 15 (Sun)**

*Registration 16:00-18:00*

*Informal get-together 18:00-20:00*

### **March 16 (Mon)**

*Registration 10:00-10:20*

*Opening 10:20-10:30*

***Session 1: Tutorial 1 10:30-11:20 (Chair: N. Suzuki and H. Yoshikawa)***

T-1 Ion Beam Sputtering for High Resolution Depth Profiling

H. J. Kang,\* D. W. Moon, and H.-I. Lee.....\*\*\*

*Break 11:20-11:35*

***Session 2: Non-destructive analysis 11:35-12:35 (Chair: N. Suzuki and H. Yoshikawa)***

O-1 Non-Destructive Depth Profiling by XPS Peak Shape Analysis

S. Hajati\* and S. Tougaard.....\*\*\*

O-2 Combination of High-Resolution RBS and Angle-Resolved XPS: Accurate Depth Profiling of Chemical States

K. Nakajima\*.....\*\*\*

*Lunch 12:35-13:45*

***Session 3: SIMS and cluster ions 13:45-15:15 (Chair: K. J. Kim and Y. Abe)***

O-3 Sputter Depth Profiling by SIMS; Calibration of SIMS Depth Scale Using Multi-layer Reference Materials

K. J. Kim,\* J. S. Jang, and T. E. Hong.....\*\*\*

O-4 Depth Profiling Analysis of Organic Materials by Using ToF-SIMS and Gradient Shaving Preparation

H. Itoh\*.....\*\*\*

O-5 Organic Depth Profiling by Cluster Ion Sputter

Y. Abe\*.....\*\*\*

*Break 15:15-15:35*

***Session 4: Sputter depth profiling 15:35-16:35 (Chair: H. J. Kang and T. Nagatomi)***

O-6 Brief History and Current Activity in ISO/TC201/SC4 for Depth Profiling

M. Suzuki\* . . . . . \*\*\*

O-7 Auger Depth Profiling Analysis Using an Inclined Holder

T. Ogiwara\* and S. Tanuma . . . . . \*\*\*

***Break 16:35-16:55***

***Session 5: Depth distribution function 16:55-17:55 (Chair: H. J. Kang and T. Nagatomi)***

O-8 Monte Carlo Study of Depth Distribution Function of Secondary Electrons

Z. J. Ding\* . . . . . \*\*\*

O-9 Evaluation of Depth Distribution Function for AR-XPS using Synchrotron Radiation Hard X-ray

H. Yoshikawa,\* H. Tanaka, M. Kimura, T. Ogiwara, T. Kimura, S. Fukushima,  
K. Kumagai, S. Tanuma, M. Suzuki, and K. Kobayashi . . . . . \*\*\*

**March 17 (Tue)**

***Session 6: Tutorial 2 9:30-10:20 (Chair: Z. J. Ding and S. Hajati)***

T-2 The Backscattering Factor for Systems with Non-uniform In-depth Profile

A. Jablonski\* . . . . . \*\*\*

***Break 10:20-10:40***

***Session 7: XPS 10:40-12:10 (Chair: Z. J. Ding and S. Hajati)***

O-10 Recent Status of Thin Film Analyses by XPS

H. Iwai,\* J. S. Hammond, and S. Tanuma . . . . . \*\*\*

O-11 Applications of XPS on Nanoscale Material Research

F. Liu,\* Z. Zhao, L. Qiu, and L. Zhao . . . . . \*\*\*

O-12 Study of SiO powder by X-ray Photoelectron Spectroscopy Analysis

H. Tohma\* . . . . . \*\*\*

***Lunch 12:10-13:30***

***Session 8: Poster (for viewing) 13:30-17:00***

***Informal get-together 18:30-20:30***

**March 18 (Wed)**

**Session 9: Poster short presentation 1 9:30-10:50 (Chair: J. H. Lee and H. Iwai)**

- P-1 Low Damage Etching of Polymer Materials for Depth Profile Analysis Using Large Ar Cluster Ion Beam  
S. Ninomiya,\* K. Ichiki, H. Yamada, Y. Nakata, T. Seki, T. Aoki, and J. Matsuo . . . . . \*\*\*
- P-2 Direct and Real-Time Surface Analysis and Imaging of Biological Samples by Probe Electrospray  
K. Hiraoka,\* L. C. Chen, D. Asakawa, S. Takeda, and T. Kubota . . . . . \*\*\*
- P-3 Depth Profiling of Polystyrene Using Charged Water Droplet Impact  
Y. Sakai,\* Y. Iijima, R. Takaishi, D. Asakawa, and K. Hiraoka . . . . . \*\*\*
- P-4 Characterisation and Optimisation of a Polyatomic Ion Source for Organic Depth Profiling  
A. J. Roberts,\* S. J. Hutton, C. J. Blomfield, I. Drummond, and S. C. Page . . . . . \*\*\*
- P-5 Test of the Consistency of Angle Resolved XPS Data for Depth Profile Reconstruction using the Maximum Entropy Method  
A. J. Roberts,\* K. Macak and K. Takahashi . . . . . \*\*\*
- P-6 Nondestructive Depth Resolved Analysis by using Grazing Exit Fluorescence-Yield X-ray Absorption Spectroscopy  
K. Shinoda,\* S. Sato, S. Suzuki, T. Uruga, H. Tanida, H. Toyokawa, Y. Terada, and Y. Takagaki . . . . . \*\*\*
- P-7 In-Depth Profile of Hf-Based Gate Insulator Films on Si Substrates Studied by Angle-Resolved Photoelectron Spectroscopy Using Synchrotron Radiation  
S. Toyoda,\* H. Kumigashira, M. Oshima, G. L. Liu, Z. Liu, and K. Ikeda . . . . . \*\*\*
- P-8 Synchrotron Radiation Photoemission Spectroscopy for Native Oxide Layer on Vanadium and VCrTa  
Y. Teraoka,\* A. Yoshigoe, and J. Harries . . . . . \*\*\*

**Break 10:50-11:10**

**Session 10: Poster short presentation 2 11:10-12:40**

**(Chair: K. Yanagiuchi and K. Takahashi)**

- P-9 Metal/Organic Interface Analysis Based on Photoelectron Spectroscopy and its Application Studies on the Next Generation Electronic Devices  
J. H. Lee\* . . . . . \*\*\*
- P-10 Depth Profiling of Perhydoropolysilazane Thin Film Using Multi Anode XPS Technique  
H. Watanabe,\* E. Tadaoka, and M. Nomoto . . . . . \*\*\*
- P-11 An Improved Backscattering Correction Equation for Wide Analytical Conditions on Quantitative Auger Analysis  
S. Tanuma\* . . . . . \*\*\*

- P-12 Calculation of Depth Distribution Functions for CuO and SiO<sub>2</sub>  
H. Shinotsuka,\* H. Yoshikawa, and S. Tanuma . . . . . \*\*\*
- P-13 Inelastic Scattering Cross Section of Si from Angular Dependent Reflection Electron Energy Loss Spectra  
H. Jin,\* H. Yoshikawa, H. Iwai, S. Tanuma, and S. Tougaard . . . . . \*\*\*
- P-14 Oxygen Enhanced Surface Roughening of Si(111) Induced by Low Energy Xe+ Ion Sputtering  
T. Miyagawa,\* K. Inoue, M. Inoue . . . . . \*\*\*
- P-15 Influences of Measurement Conditions on Etching Rate of GaAs/AlAs Superlattice in Auger Electron Spectroscopy Sputter Depth Profiling  
T. Nagatomi,\* T. Bungo, and Y. Takai . . . . . \*\*\*
- P-16 In-Situ Observation of the Reaction between Iron and Carbon in TEM  
N. Ishikawa,\* T. Aoyagi, T. Kimura, K. Furuya, H. Harada, and T. Inami . . . . . \*\*\*
- P-17 Diagnosis and Cleaning of Carbon Contamination on SiO<sub>2</sub> Thin Film  
A. Kurokawa, K. Odaka,\* Y. Azuma, T. Fujimoto, I. Kojima . . . . . \*\*\*

**Lunch 12:40-13:40**

**Session 11: Poster presentation 1 13:40-14:40 (Chair: M. Arai and H. Itoh)**

Odd number

**Session 12: Poster presentation 2 14:40-15:40 (Chair: T. Ogiwara and H. Tohma)**

Even number

**Korea-Japan-China symposium 15:40-19:00**

**Closing 19:00-19:10**

## Contents

**Timetable (tentative)****March 15 (Sun)**

Program	Time	Chairpersons & Remarks
<b>Registration</b>	16:00-18:00	At Lobby of the TOYOKO Inn Naha Asahibashi-Ekimae Hotel. Please see
<b>Informal get-together</b>	18:00-20:00	Please come to Registration Desk.

**March 16 (Mon)**

Program	Time	Remarks
<b>Registration</b>	10:00-10:20	Registration on March 15 is strongly recommended.
<b>Opening</b>	10:20-10:30	
<b>Session 1: Tutorial 1</b> T-01 H. J. Kang	10:30-11:20	Chair: N. Suzuki and H. Yoshikawa
<b>Break</b>	11:20-11:35	
<b>Session 2: Non-destructive analysis</b> O-01 S. Hajati O-02 K. Nakajima	11:35-12:35	Chair: N. Suzuki and H. Yoshikawa
<b>Lunch</b>	12:35-13:45	Included in registration fee. Please see <a href="http://www.sasj.jp/iSAS/iSAS09/social_prg.html">http://www.sasj.jp/iSAS/iSAS09/social_prg.html</a> .
<b>Session 3: SIMS and cluster ions</b> O-03 K. J. Kim O-04 H. Itoh O-05 Y. Abe	13:45-15:15	Chair: K. J. Kim and Y. Abe
<b>Break</b>	15:15-15:35	
<b>Session 4: Sputter depth profiling</b> O-06 M. Suzuki O-07 T. Ogiwara	15:35-16:35	Chair: H. J. Kang and T. Nagatomi
<b>Break</b>	16:35-16:55	
<b>Session 5: Depth distribution</b> O-08 Z. J. Ding O-09 H. Yoshikawa	16:55-17:55	Chair: H. J. Kang and T. Nagatomi

**March 17 (Tue)**

Program	Time	Remarks
<b>Session 6: Tutorial 2</b> T-02 A. Jablonski	9:30-10:20	Chair: Z. J. Ding and S. Hajati
<b>Break</b>	10:20-10:40	
<b>Session 7: XPS</b> O-10 H. Iwai O-11 F. Liu O-12 H. Tohma	10:40-12:10	Chair: Z. J. Ding and S. Hajati
<b>Lunch</b>	12:10-13:30	NOT included in registration fee. Please see <a href="http://www.sasj.jp/iSAS/iSAS09/social_prg.html">http://www.sasj.jp/iSAS/iSAS09/social_prg.html</a> .
<b>Session 8: Poster (for viewing)</b>	13:30-17:00	Presenters are requested to put their posters on the panel.
<b>Informal get-together</b>	18:30-20:30	Details are informed at the conference site.

**March 18 (Wed)**

Program	Time	Remarks
<b>Session 9: Poster short presentation</b> P-01 ~ P-08	9:30-10:50	Chair: J. H. Lee and H. Iwai
<b>Break</b>	10:50-11:10	
<b>Session 10: Poster short presentation</b> P-09 ~ P-17	11:10-12:40	Chair: K. Yanagiuchi and K. Takahashi
<b>Lunch</b>	12:40-13:40	Included in registration fee. Please see <a href="http://www.sasj.jp/iSAS/iSAS09/social_prg.html">http://www.sasj.jp/iSAS/iSAS09/social_prg.html</a> .
<b>Session 11: Poster presentation 1</b> Odd number	13:40-14:40	Chair: M. Arai and H. Itoh
<b>Session 12: Poster presentation 2</b> Even number	14:40-15:40	Chair: T. Ogiwara and H. Tohma
<b>Korea-Japan-China symposium</b>	15:40-19:00	Details are informed at the conference site.
<b>Closing</b>	19:00-19:10	